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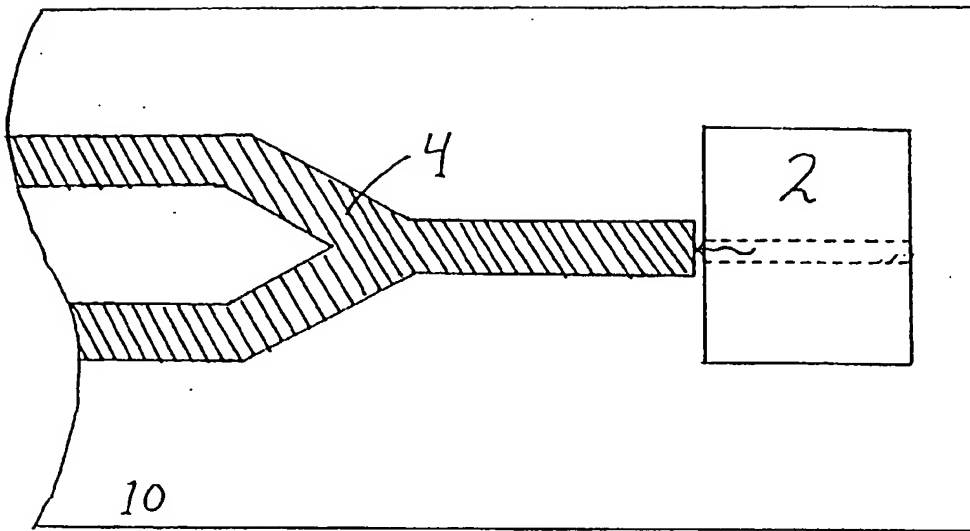


Fig. 1 (Prior art)

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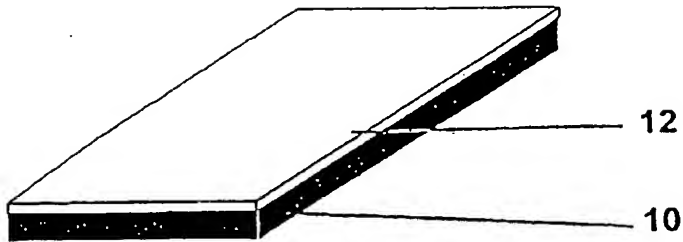


Fig. 2

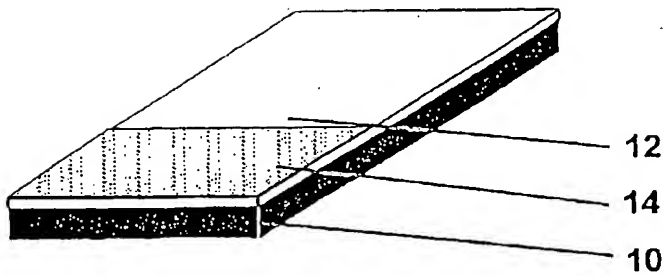


Fig. 3

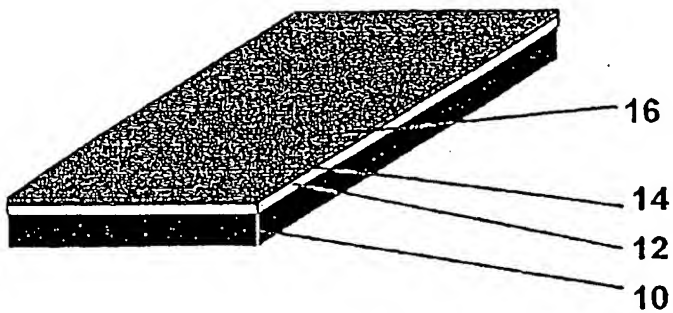


Fig. 4

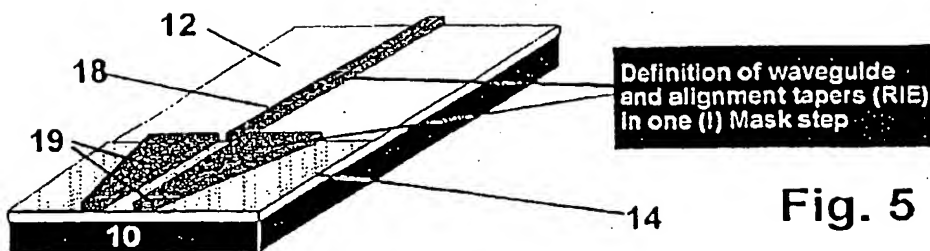


Fig. 5

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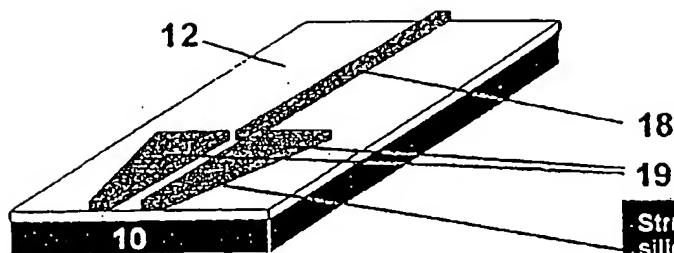


Fig. 6

Structuring of poly-silicon etch stop by wet-etching

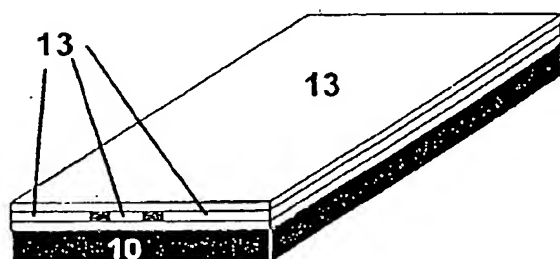
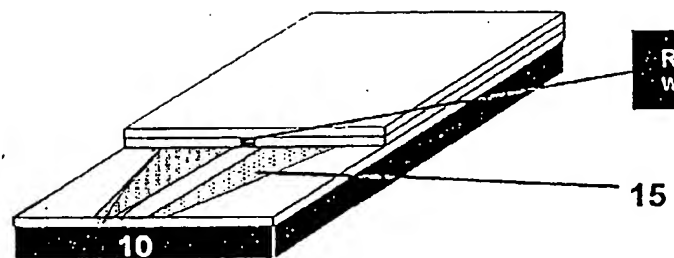


Fig. 7



RIE etching of the waveguide facet

Fig. 8

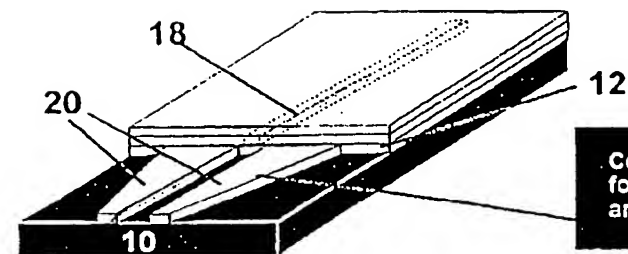


Fig. 9

Completion of RIE etch for facet and alignment tapers

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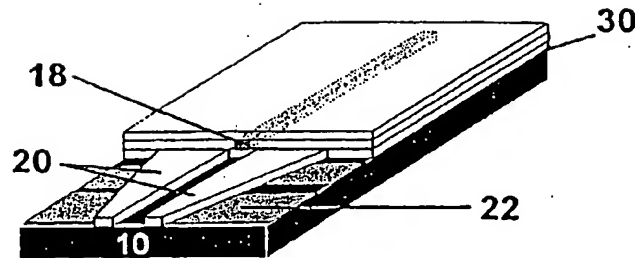


Fig. 10

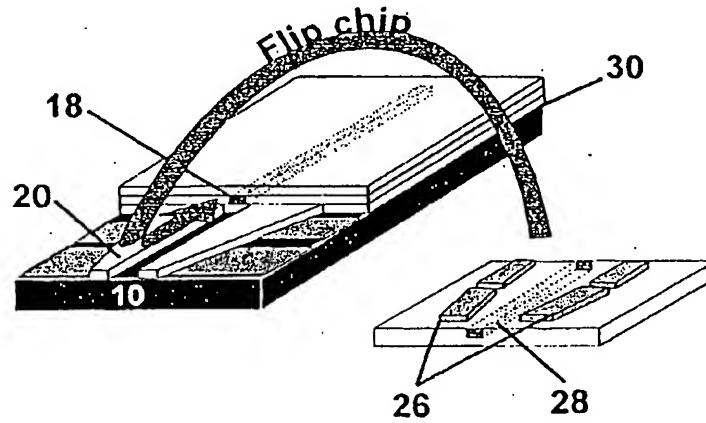


Fig. 11

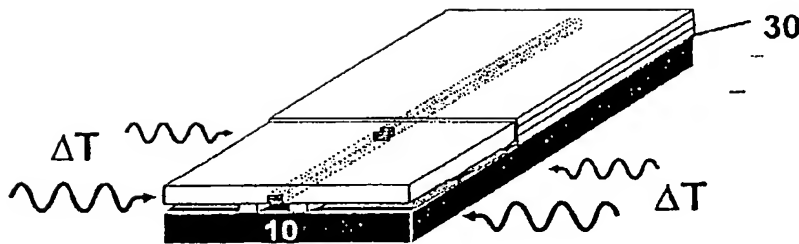


Fig. 12

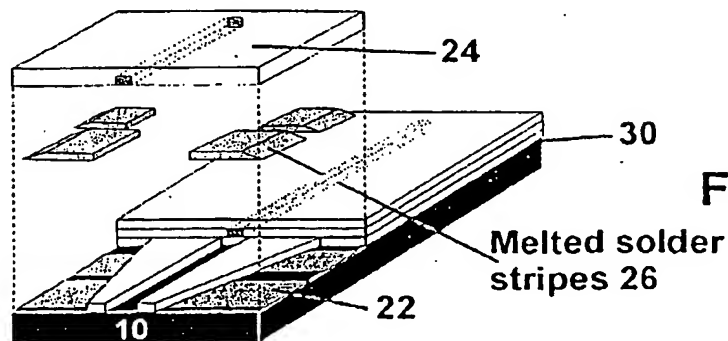


Fig. 13

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Fig. 14

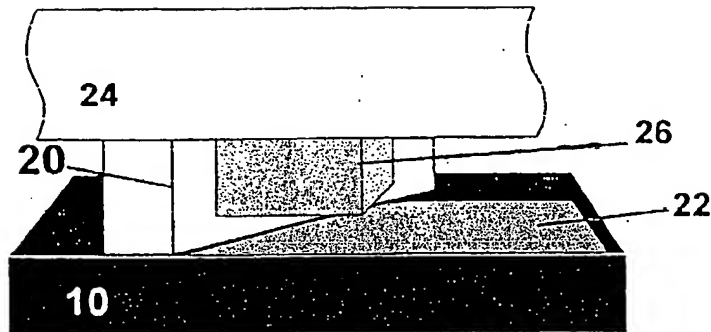
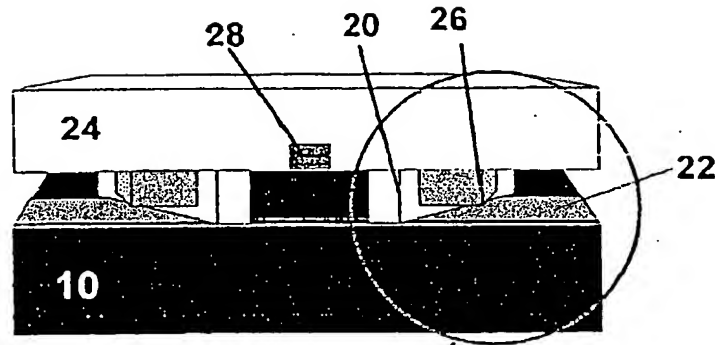
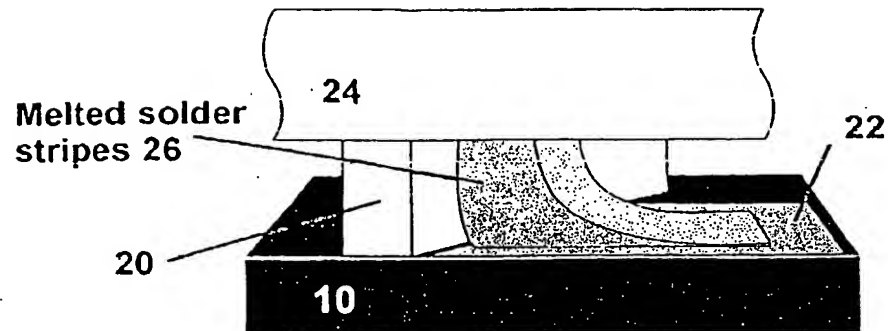
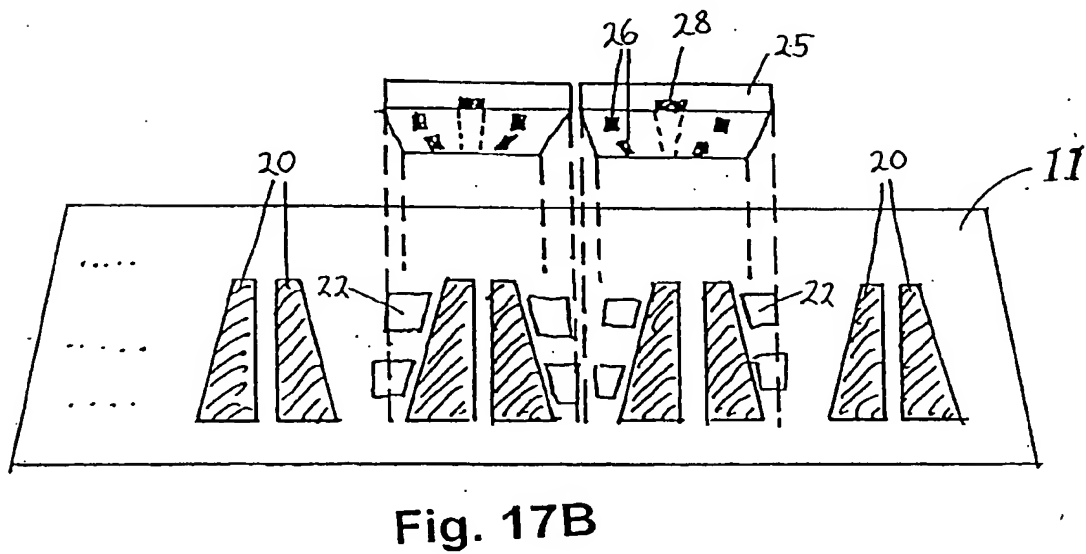
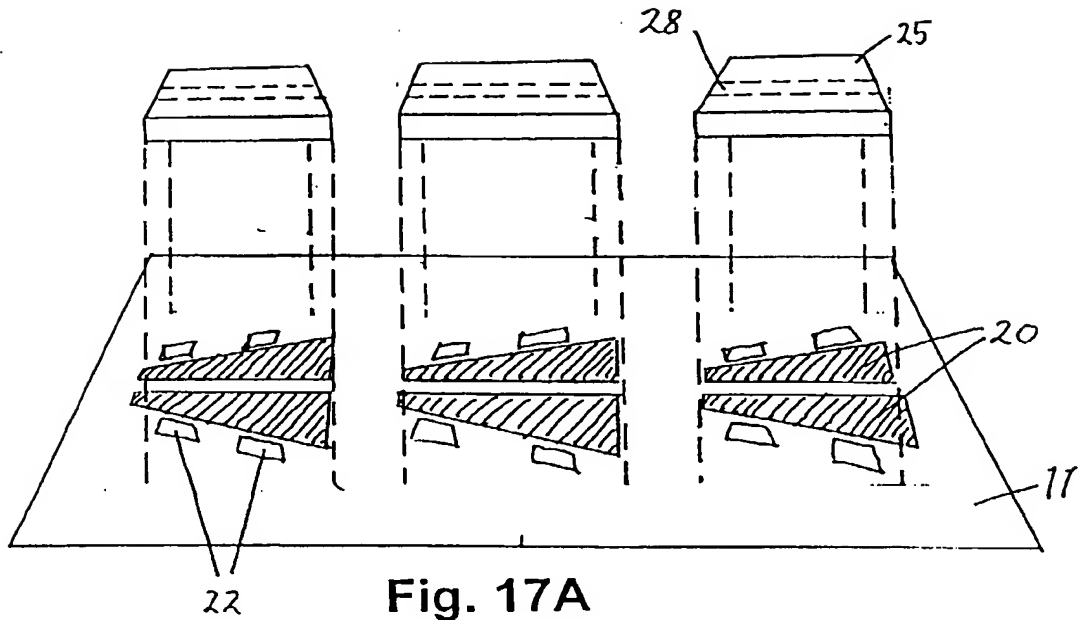


Fig. 15

Fig. 16



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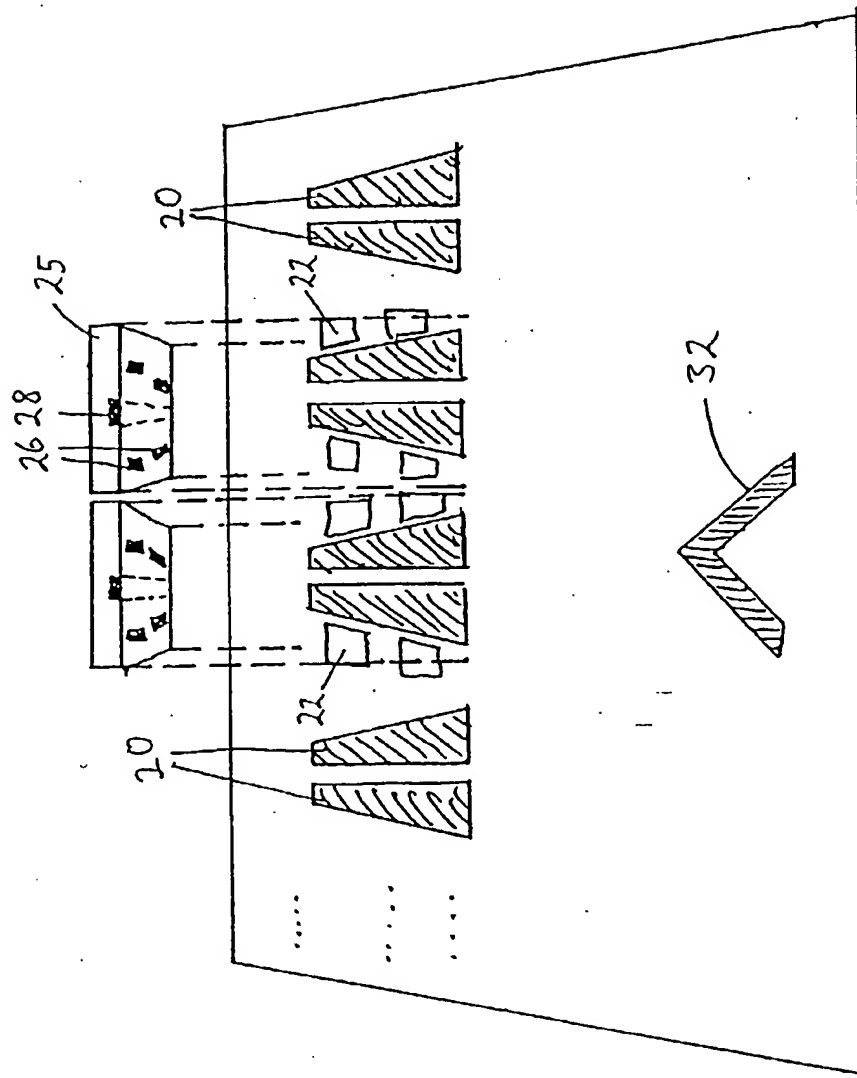


Fig. 18

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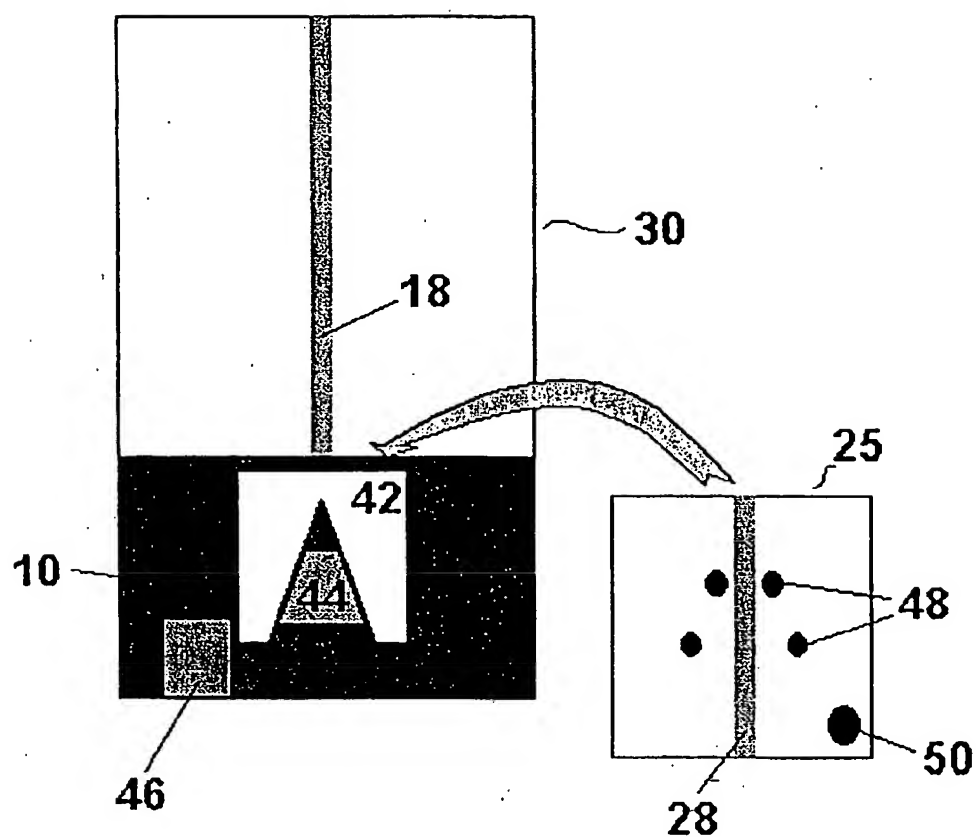


Fig. 19



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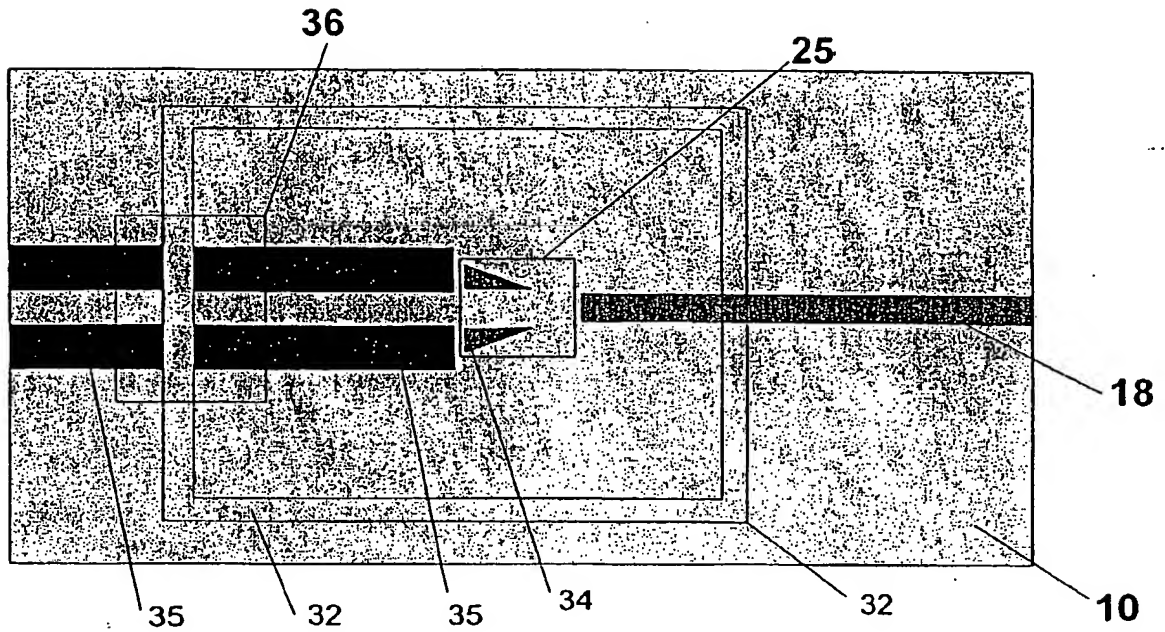


Fig. 20A

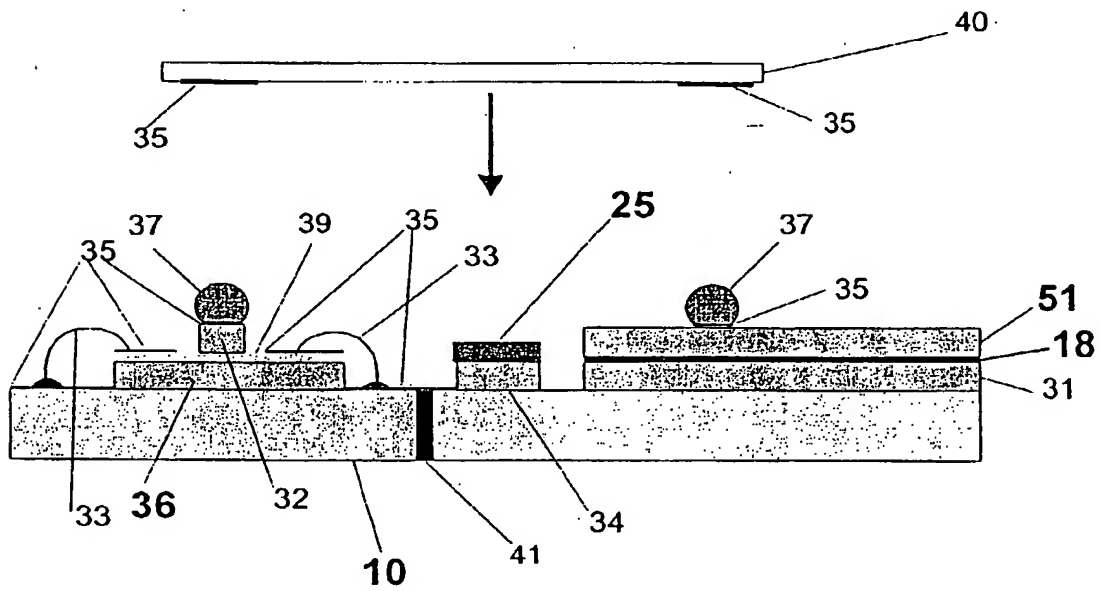


Fig. 20B